



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9191**
Makoto AKIZUKI et al. : **Docket No. 2001-1897**
Serial No. 10/025,899 : **Group Art Unit 1762**
Filed December 26, 2001 : **Examiner B. Pianalto**

**METHOD FOR FORMING GAS CLUSTER AND
METHOD FOR FORMING THIN FILM**

PETITION FOR EXTENSION OF TIME

Assistant Commissioner for Patents,
Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED TO
FORGIVE ANY DEFICIENCY
IN THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of
August 7, 2002.

The fee of \$930.00 is

- (X) submitted herewith.
() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is
enclosed.
() Small entity status of this application is established by a Small Entity Status Assertion
which
() is enclosed.
() has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

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